

**PATENT**  
**29936/39481**

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Applicant: Ihl Hyun Cho  
Serial No.: To be assigned  
Filed: July 11, 2003 (herewith)  
For: Method of Manufacturing  
Semiconductor Devices  
Group Art Unit: To be assigned  
Examiner: To be assigned

) I hereby certify that this Patent  
) Application Transmittal and the  
) documents referred to as enclosed  
) therewith are being deposited with the  
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Commissioner for Patents  
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Sir:

Submitted herewith for consideration by the examiner are copies of the documents identified on the attached PTO SB/08. Entry and consideration of the submitted documents is solicited.

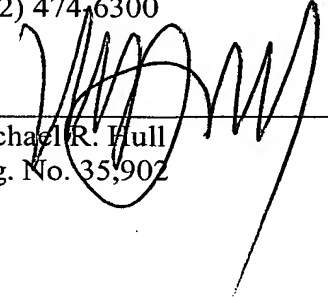
The Commissioner is authorized to charge any fee deficiency required by this paper, or credit any overpayment, to Deposit Account No. 13-2855.

Respectfully submitted,

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July 11, 2003

By:

  
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Substitute for form 1449A/PTO  <b>INFORMATION DISCLOSURE STATEMENT BY APPLICANT</b>  <i>(use as many sheets as necessary)</i>				<b>Complete if Known</b>	
				Application Number	Not Yet Assigned
				Filing Date	July 11, 2003
				First Named Inventor	Ihl Hyun Cho
				Art Unit	Not Yet Assigned
				Examiner Name	Not Yet Assigned
Sheet	1	of	1	Attorney Docket Number	29936/39481

U.S. PATENT DOCUMENTS					
Examiner Initials*	Cite No. <sup>1</sup>	Document Number	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		Number-Kind Code <sup>2</sup> (if known)			
		5,668,035	09-16-1997	Fang et al.	

FOREIGN PATENT DOCUMENTS						
Examiner Initials*	Cite No. <sup>1</sup>	Foreign Patent Document	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear	T <sup>6</sup>
		Country Code <sup>3</sup> -Number <sup>4</sup> -Kind Code <sup>5</sup> (if known)				

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OTHER PRIOR ART – NON PATENT LITERATURE DOCUMENTS			
Examiner Initials*	Cite No. <sup>1</sup>	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T <sup>2</sup>
		Tadahiro Ohmi et al., "Dependence of Thin-Oxide Films Quality on Surface Microroughness," IEEE Transactions on Electron Devices, Vol. 39, No. 3, pp. 537-545 (March 1992)	
		C.T. Liu et al., "Severe Thickness Variation of Sub-3nm Gate Oxide Due to Si Surface Faceting, Poly-Si Intrusion, and Corner Stress," 1999 Symposium on VLSI Technology Digest of Technical Papers, pp. 75-76	

Examiner Signature		Date Considered	
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